

Atomic and electronic structures of Si-dangling bonds in quasi-free standing monolayer graphene (QFMLG)



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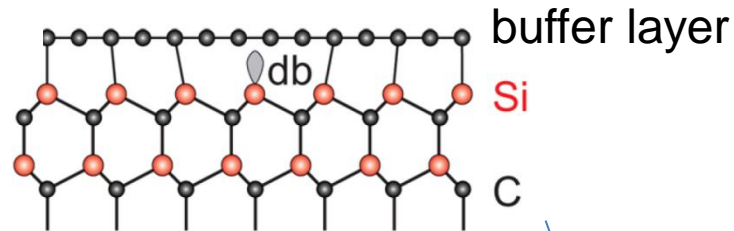


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graphene on SiC(0001)

side view



annealing in vacuum
or inert gas

H intercalation

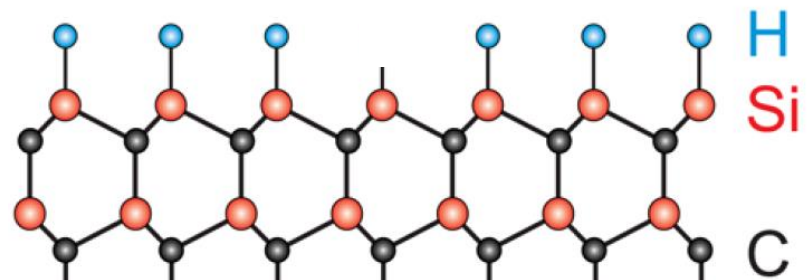
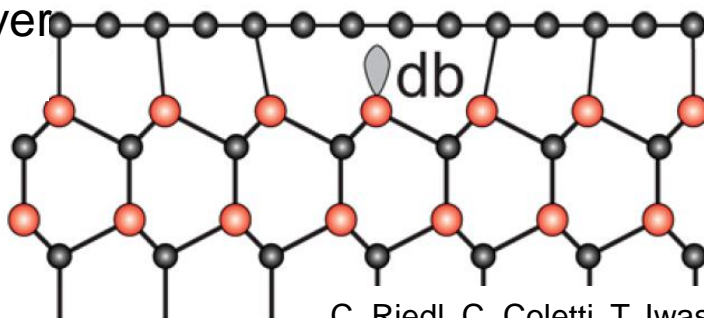
epitaxial monolayer graphene (EMLG)



quasi-free-standing monolayer
graphene (QFMLG)



buffer layer

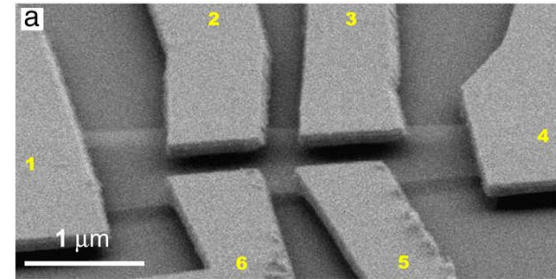


mobility of graphene

free standing graphene

: mobility = $2 \times 10^5 \text{ cm}^2 \cdot \text{V}^{-1} \cdot \text{s}^{-1}$

- difficult to handle, make contacts



Bolotin, et.al., solid state communications 146, 351 (2008).

graphene on SiO_2 : mobility = $4.6 \times 10^4 \text{ cm}^2 \cdot \text{V}^{-1} \cdot \text{s}^{-1}$

Chen, et.al., Nature Nanotech. 3, 206 (2008).

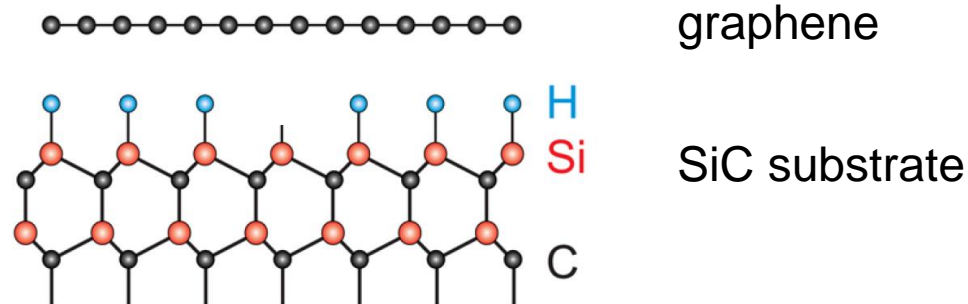
graphene on hBN: mobility = $1.4 \times 10^5 \text{ cm}^2 \cdot \text{V}^{-1} \cdot \text{s}^{-1}$

Wang, et.al., Science 342, 614 (2013).

- mobility decreases due to substrate's phonon, charged impurity, and disorder
- Graphene needs to be transferred from graphite or growth substrate.

quasi-free-standing monolayer graphene (QFMLG)

graphene epitaxially grown on H-terminated SiC(0001) surface

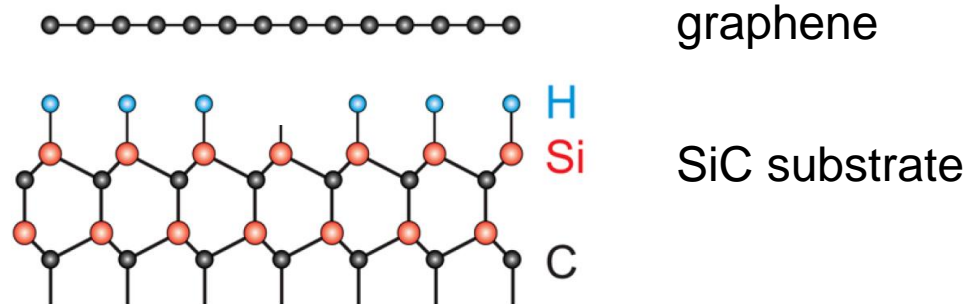


Riedl, et.al., Phys. Rev. Lett. **103**, 246804 (2009)

- H atoms are intercalated at the interface to terminate Si bonds of SiC
- the reported highest mobility $6000 \text{ cm}^2 \cdot \text{V}^{-1} \cdot \text{s}^{-1}$ Ciuk et al., Carbon 101, 431 (2016).
- Si dangling bonds (= H vacancies) may remain at the interface and act as carrier scattering centers?

quasi-free-standing monolayer graphene (QFMLG)

graphene epitaxially grown on H-terminated SiC(0001) surface



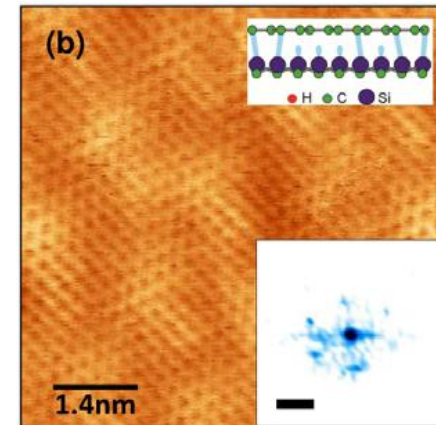
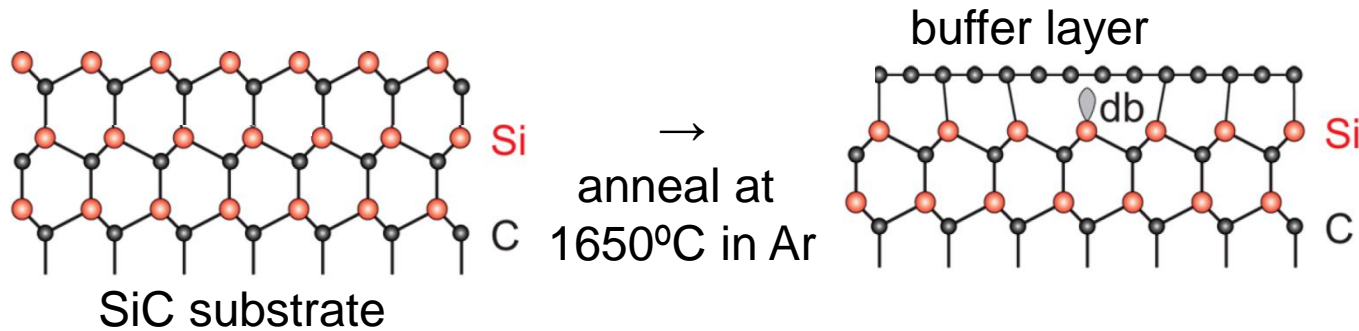
In this work, we studied:

the atomic/electronic structure of Si dangling bonds (= H vacancies)
at the interface of QFMLG

by scanning tunneling microscopy (STM), atomic force microscopy (AFM),
and DFT calculation.

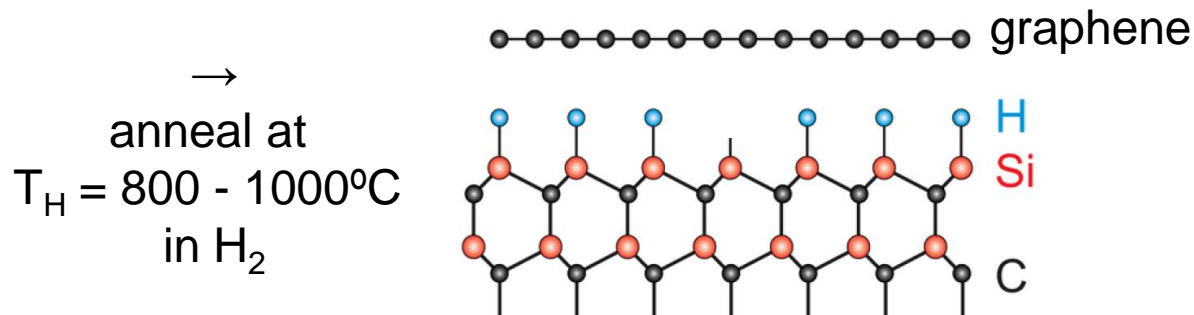
experiment

1. formation of buffer layer



STM of buffer layer
Goler, Carbon 51, 249 (2013).

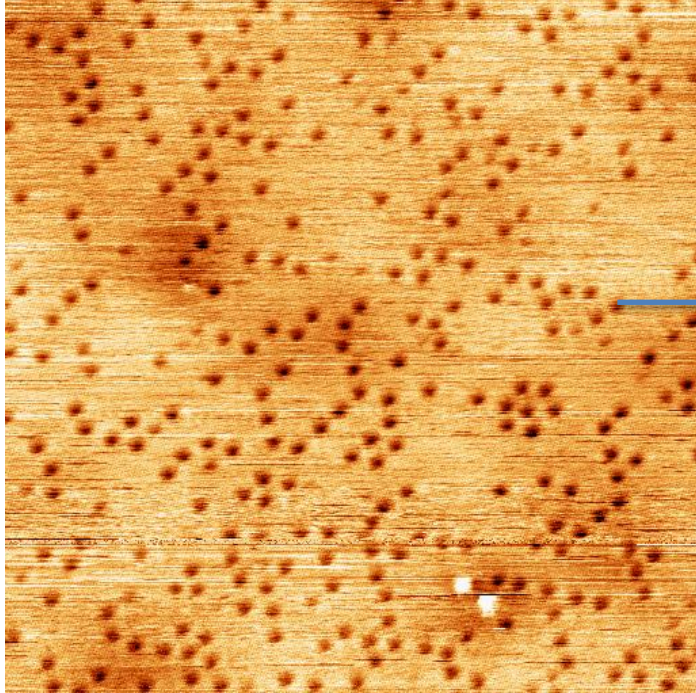
2. H intercalation



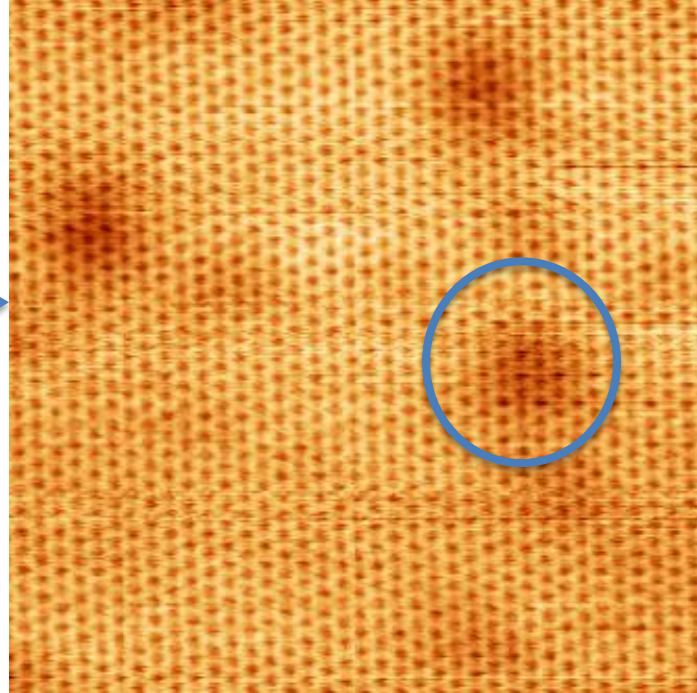
3. characterization

- RT-STM
- LT-STM/AFM (5K)

RT-STM on QFMLG ($T_H = 800^\circ\text{C}$)



50 nm, 0.6 V, 0.4 nA



8 nm, 0.5 V, 0.1 nA

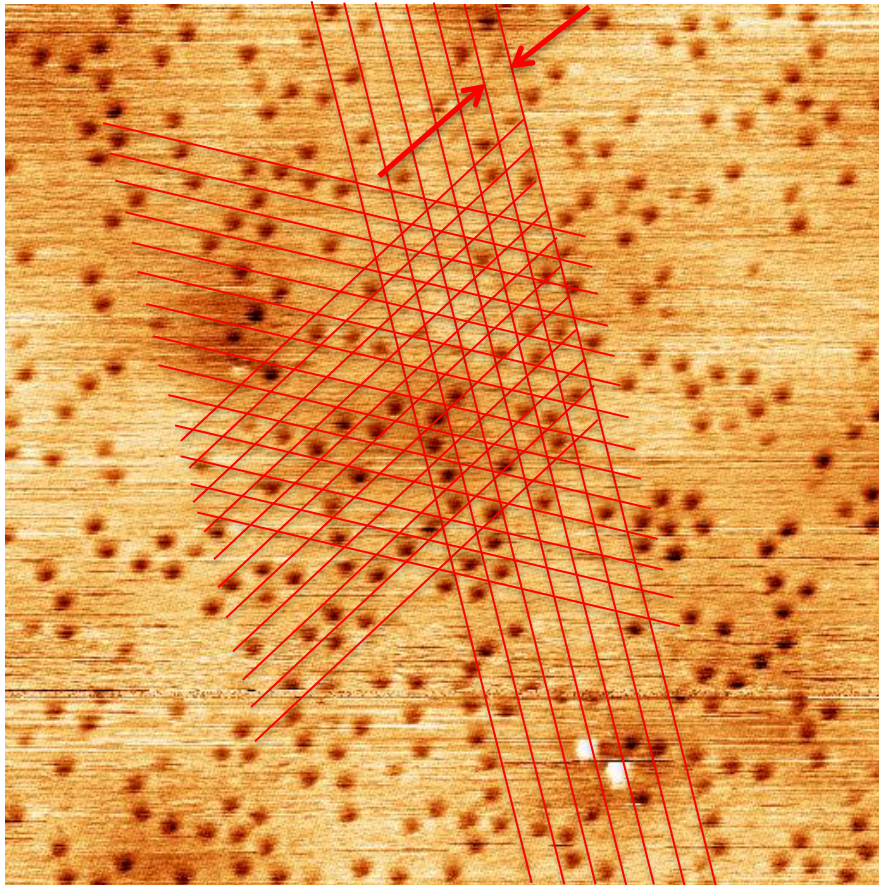
- dark features
width: 1.5 nm
density: 10^{13} cm^{-2}

-> Si dangling bonds?

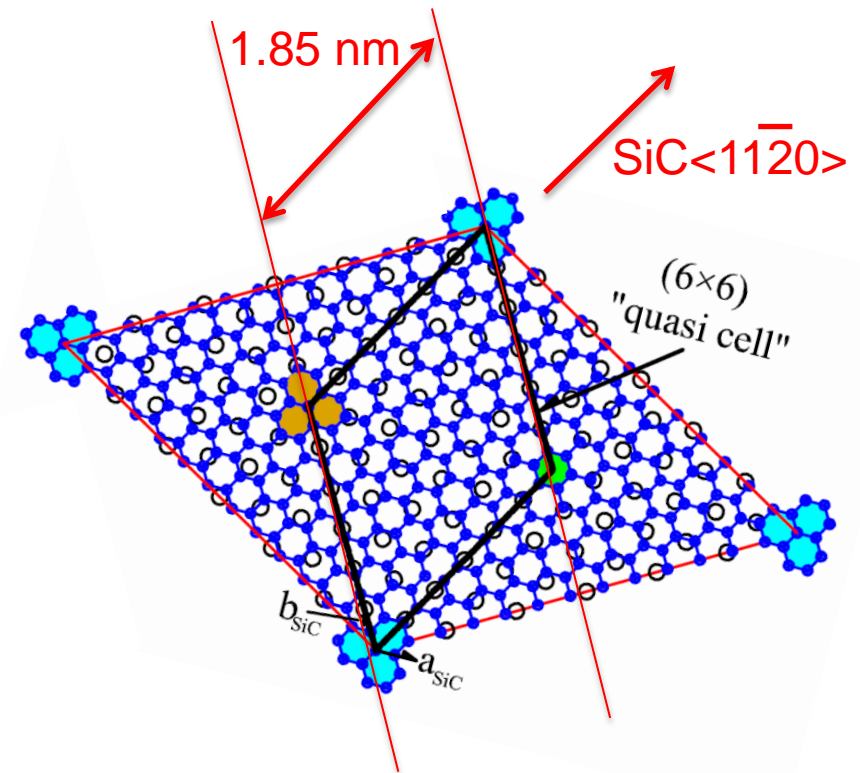
distribution of the features

SiC $\langle 11\bar{2}0 \rangle$ directions
spacing of 1.8 nm

- ~ SiC 6×6 cell
- ~ quasi cell of moiré pattern produced by graphene and SiC(0001) lattices



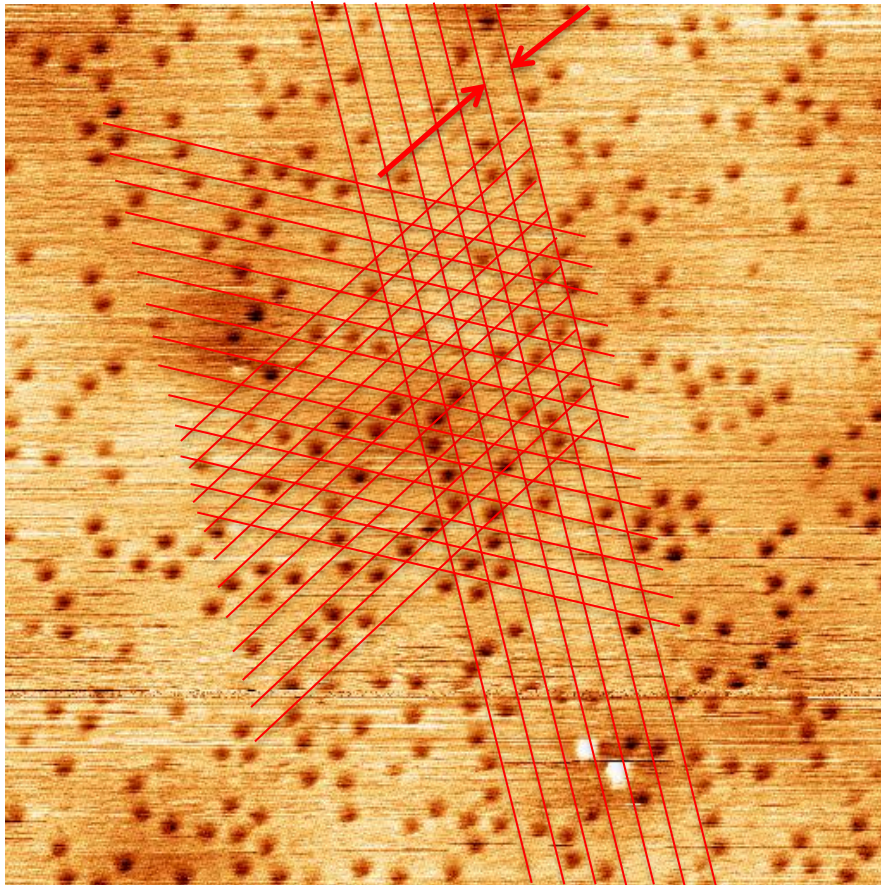
50 nm



blue: graphene $a = 0.24589$ nm
white: a = Si 0.30805 nm

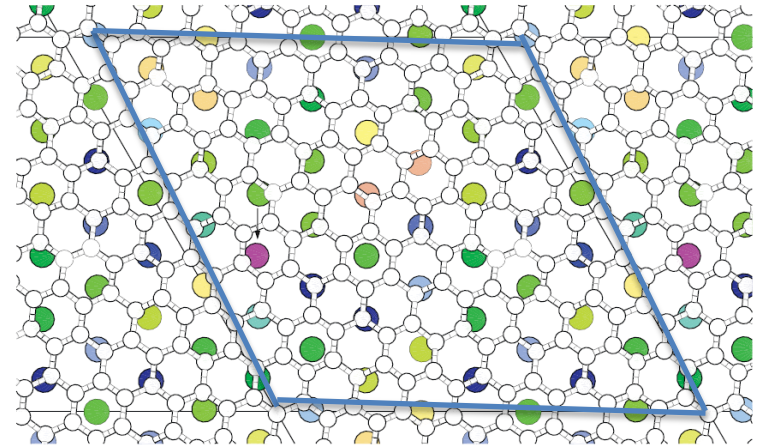
distribution of the features

SiC $\langle 11\bar{2}0 \rangle$ directions
spacing of 1.8 nm



50 nm

spatial distribution of hydrogenation energy
on Si sites in $4\sqrt{3} \times 4\sqrt{3}$ quasi cell



variation ~ 1 eV

dark blue: the least favored H adsorption sites

G. Sclauzero, A. Pasquarelo, Appl. Surf. Sci. 291, 64 (2014).

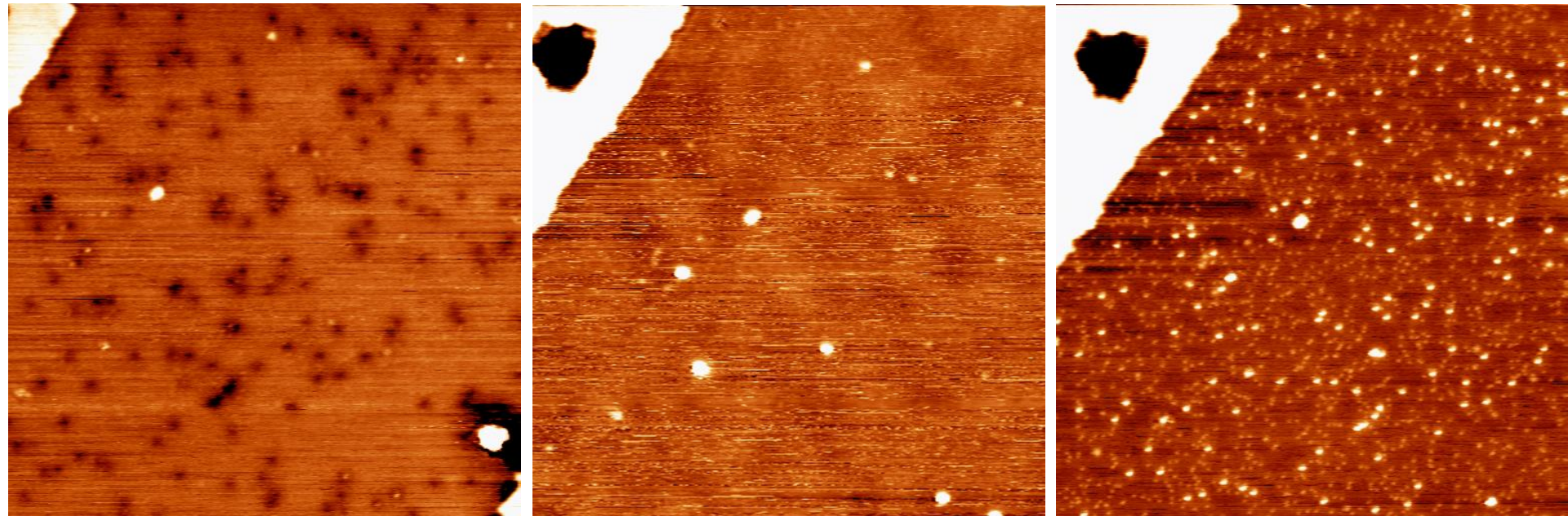
The least favored H adsorption site remain vacant in each quasi cell, and they are observed as the dark features.

RT-STM on QFMLG ($T_H = 1000^\circ\text{C}$)

bias $V = -1.5\text{V}$

0.5V

+1.5V

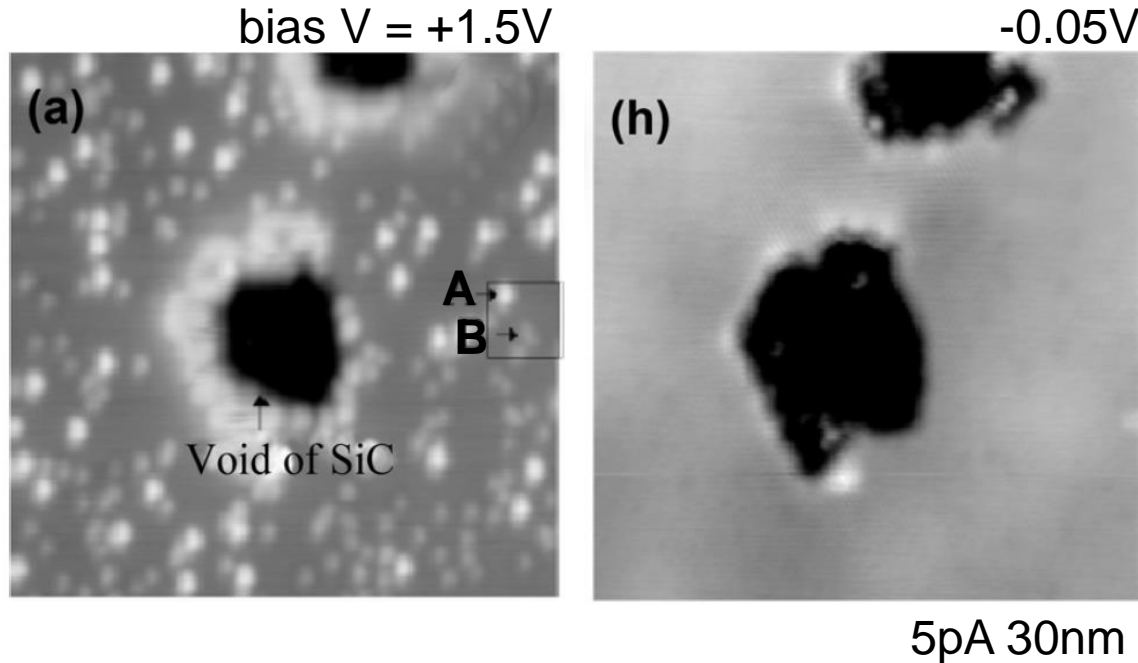


0.1nA 100nm

- The density of the features is $5 \times 10^{11} \text{ cm}^{-2}$, less than the sample $T_H = 800^\circ\text{C}$.
- The contrasts of the features vary with bias V .
- There are 2 types of features. (brighter and less bright)

LT-STM on QFMLG ($T_H = 1000^\circ\text{C}$)

at 5K



- There are two types of features. (brighter A and less bright B)
- The contrasts vary with bias V .

Dr. Gerhard Mayer

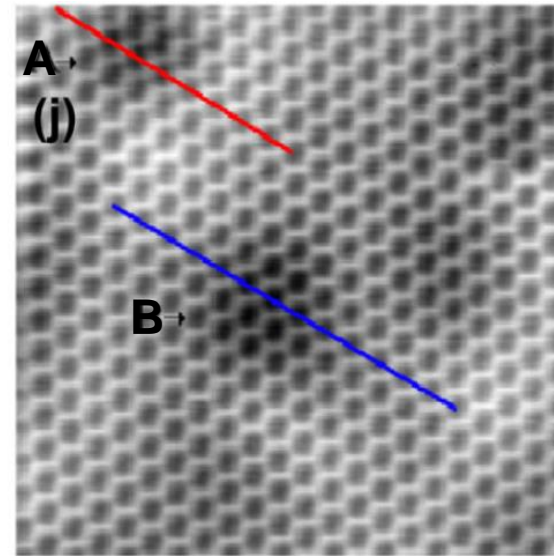
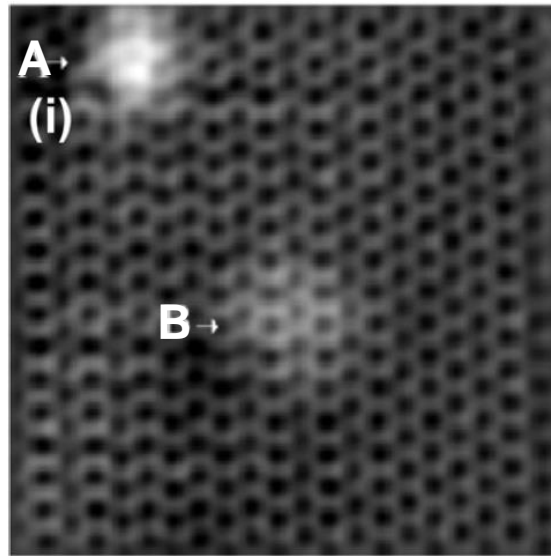
IBM Zurich



- High magnification images

STM

AFM

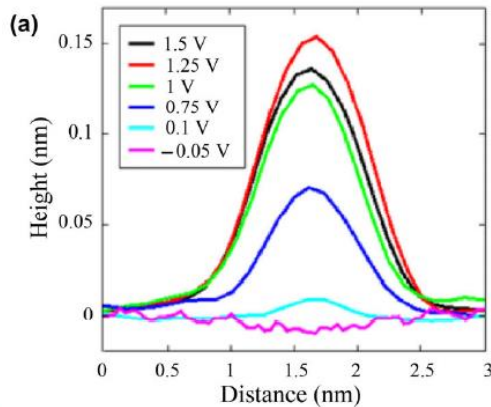


0.1V, 20pA, 4nm

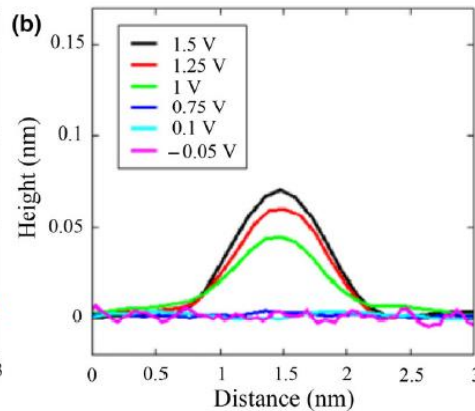
4nm

- profiles on features

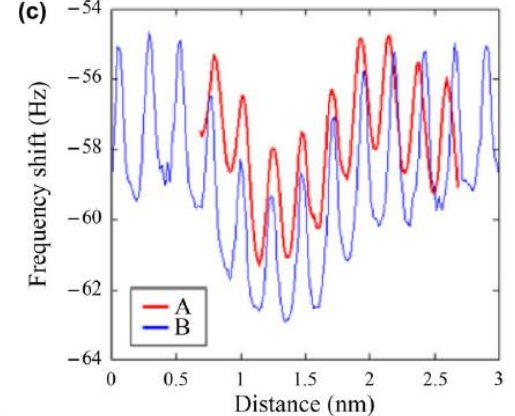
STM – feature A



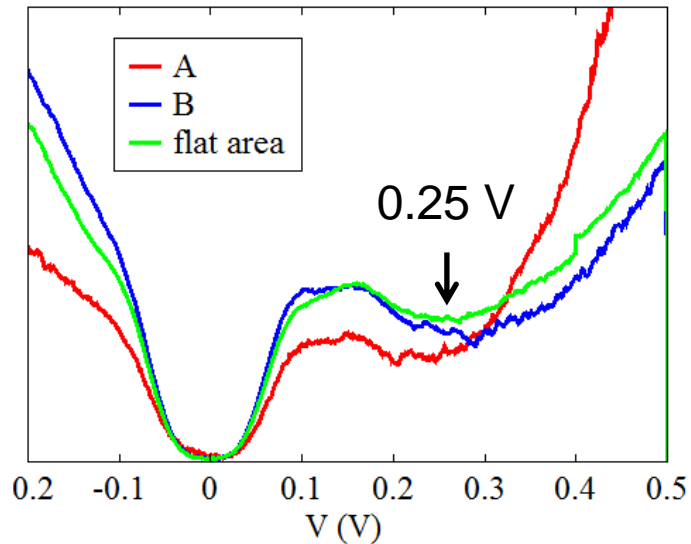
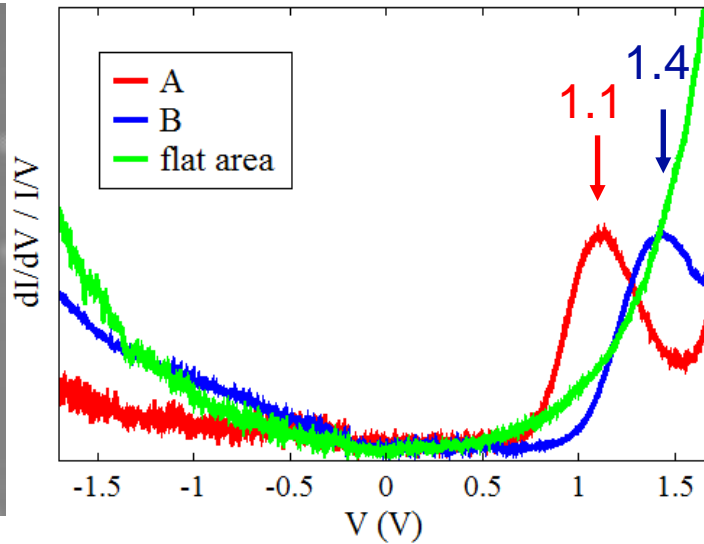
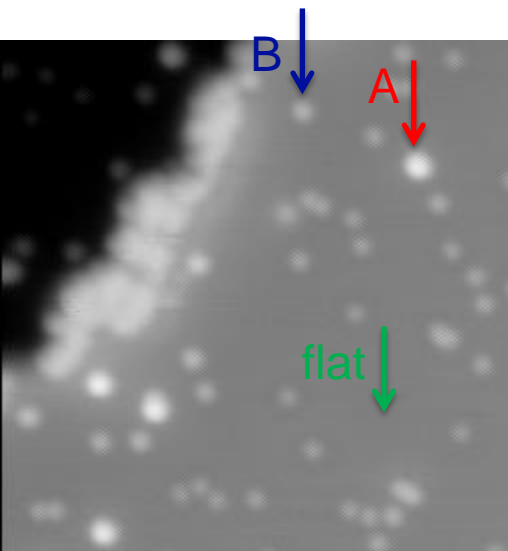
STM – feature B



AFM – features A and B



STS



1.8V, 0.01nA, 20 nm

peak at 1.1 V
1.4 V

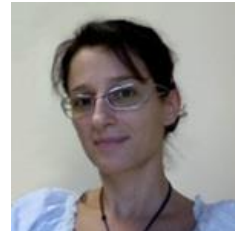
gap like feature at 0 V
dip at 0.25 V

-> p doping of QFMLG

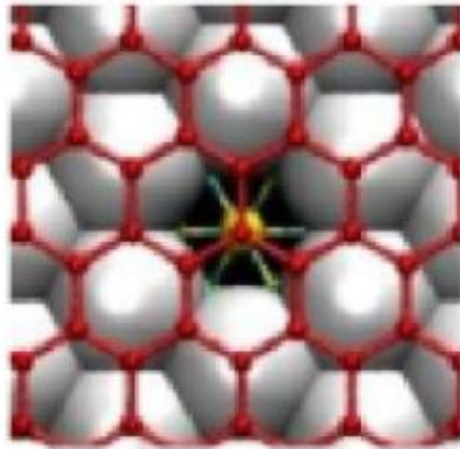
DFT calculation: models

Si dangling bonds' cluster (H vacancies)

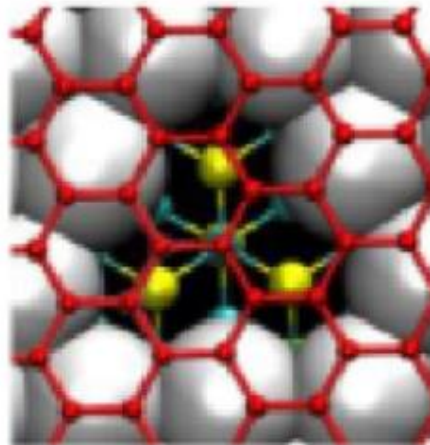
Dr Valentina Tozzini
CNR Pisa



1 H vacancy

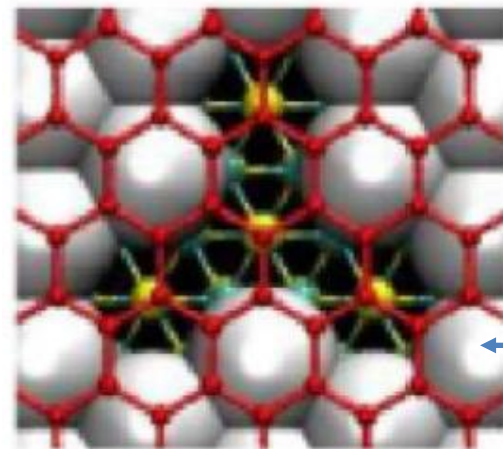


3 H vacancies



-> feature A

4 H vacancies

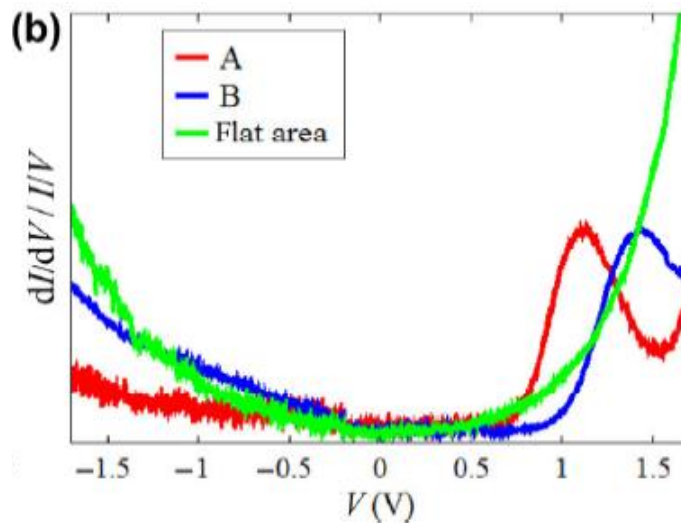


-> feature B

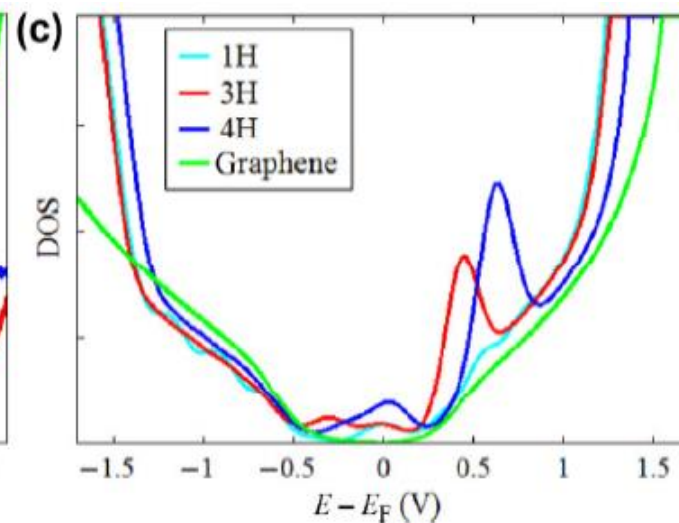
- Even in the 4 H vacancies, Si atoms do not covalently bond to graphene C, remaining dangling bonds. It acts as a charged scattering center.

DFT calculation: DOS

experimental data of STS

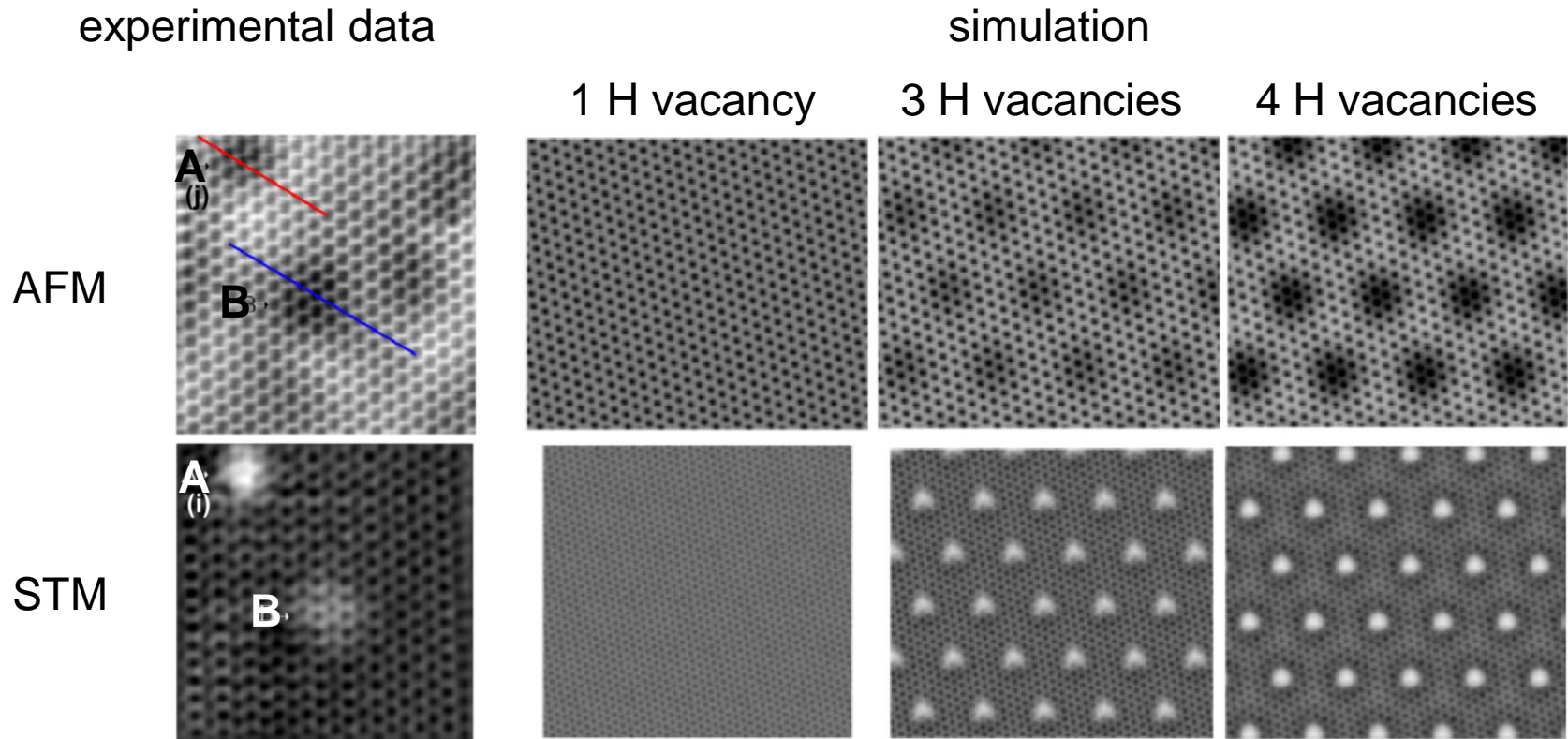


calculated DOS



- 1H model: no peak
- 3H and 4H models have peaks in the empty state, originating from the Si dangling bonds.
- The relative energy positions represent the peaks in experimental data on the features A and B, respectively.

DFT calculation: simulated AFM/STM



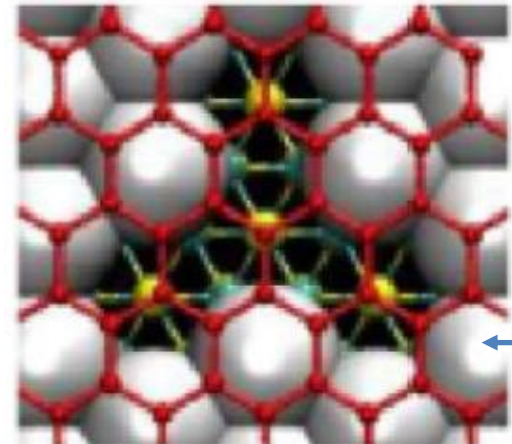
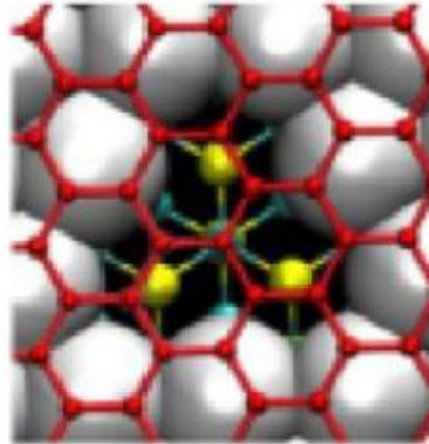
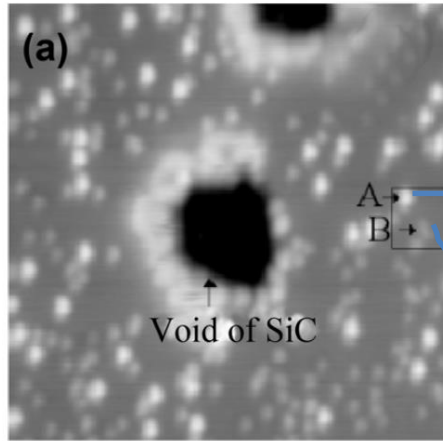
- The simulated STM/AFM images of 3H and 4H best fit the experimental data on the features A and B, respectively.

conclusion

STM

3 H vacancies

4 H vacancies



- We investigated the structure of Si dangling bonds (H vacancies) of QFMLG by STM, AFM and DFT calculation.
- We could identify 2 types of Si dangling bonds' clusters (H vacancies) including 3H and 4H vacancies.
- Even in the 4H vacancies, Si atoms do not covalently bond to graphene C, remaining dangling bonds.
- the density of Si dangling bonds: the sample formed at $T_H = 800^\circ\text{C} > 1000^\circ\text{C}$



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graphene growth

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